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Notice of Allowability	Application No.	Applicant(s)	
	10/774,589	TANABE ET AL.	
Notice of Allowability	Examiner	Art Unit	
	DAVID VU	2818	
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.			
1. This communication is responsive to <u>02/10/04</u> .			
2. The allowed claim(s) is/are <u>1-33</u> .			
3. The drawings filed on 10 February 2004 are accepted by the Examiner.			
4.			
Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 02/10/04&06/01/04 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. Interview Summary Paper No./Mail Dal 7. Examiner's Amendr 8. Examiner's Stateme 9. Other	e	
David Nelms Supervisory Patent Examiner Technology Center 2800			

Application/Control Number: 10/774,589 Page 2

Art Unit: 2818

DETAILED ACTION

Reason for allowance

1. The following is an examiner's statement of reason for allowance: None of the references of record teaches or suggests a method for fabricating a semiconductor integrated circuit device, comprising the steps of: (a) forming an isolation groove between a plurality of active regions in a first major surface of a wafer; then performing thermal oxidation treatment to a silicon surface portion over one of the active regions to form an insulating film under the wet oxidative atmosphere in the processing chamber by keeping the synthesized water vapor in a gaseous state and feeding it into a processing chamber to form a wet oxidative atmosphere.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance".

Conclusion

2. Any inquiry concerning this communication or earlier communications from the examiner should be directed to David Vu whose telephone number is 571-272-1798. The examiner can normally be reached on Monday-Friday 8:00am-5:30pm.

Application/Control Number: 10/774,589 Page 3

Art Unit: 2818

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on 571-272-1787. The fax phone numbers for the organization where this application or proceeding is assigned is (703) 872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR, Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

DV

David Vu.

February 05, 2005.

David Nelms

Supervisory Patent Examiner Technology Center 2800